

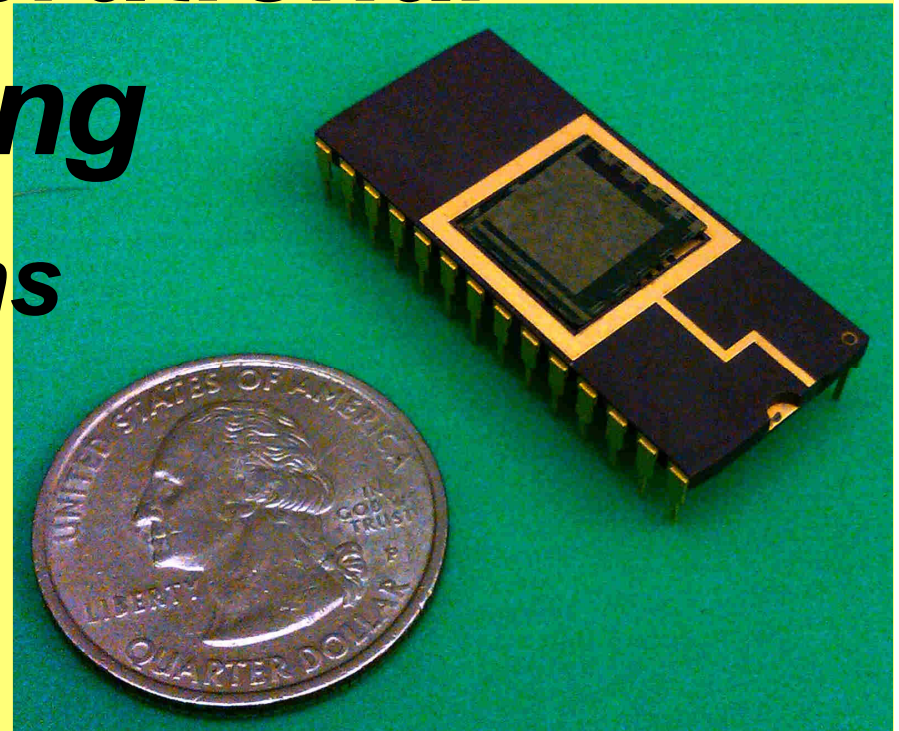
# ***Piezoelectric Vibrational Energy Harvesting MEMS-based solutions***

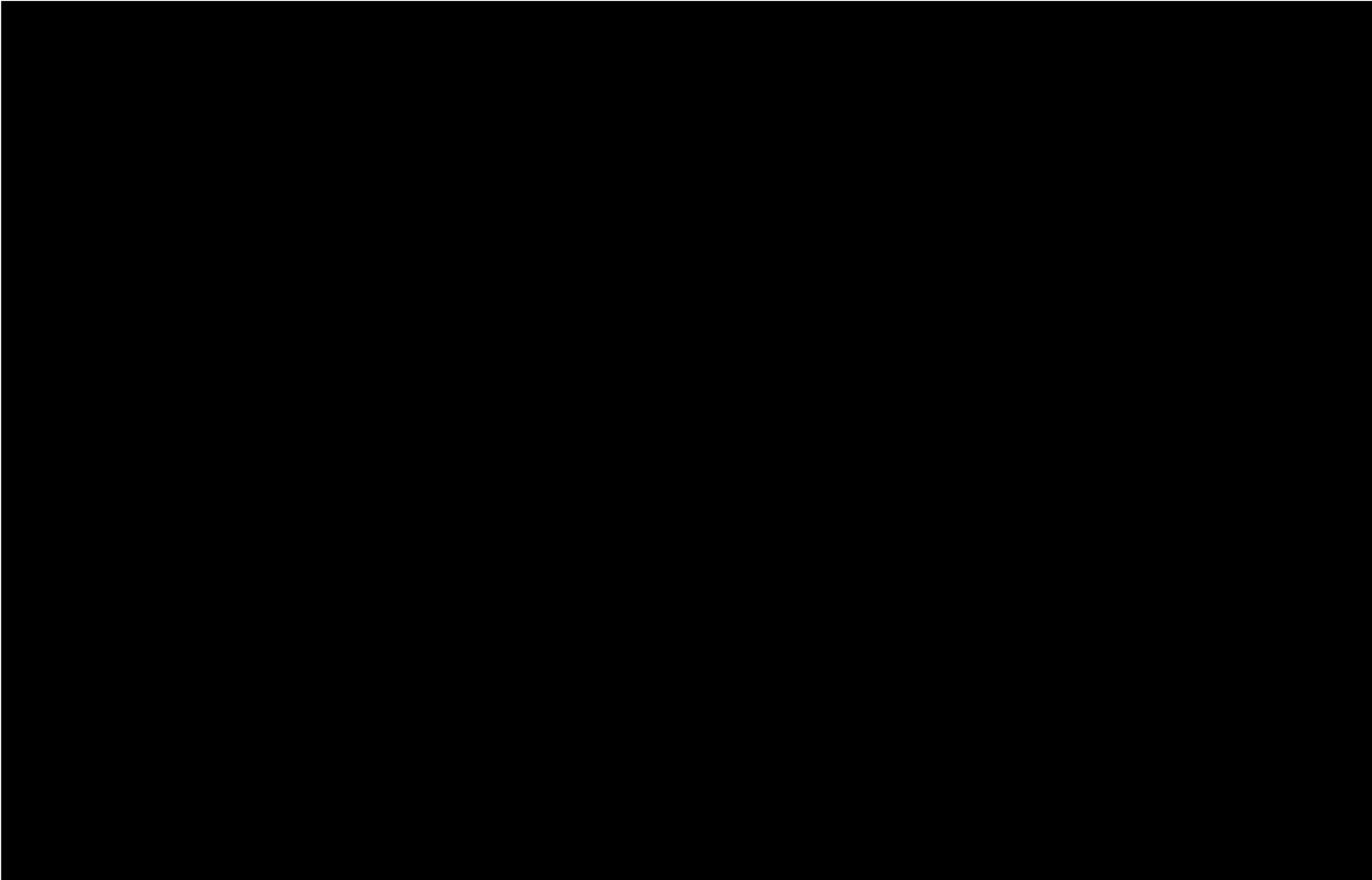
**Robert G. Andosca**

Founder, President and CTO

**Junru Wu**

Founder and Technical Fellow





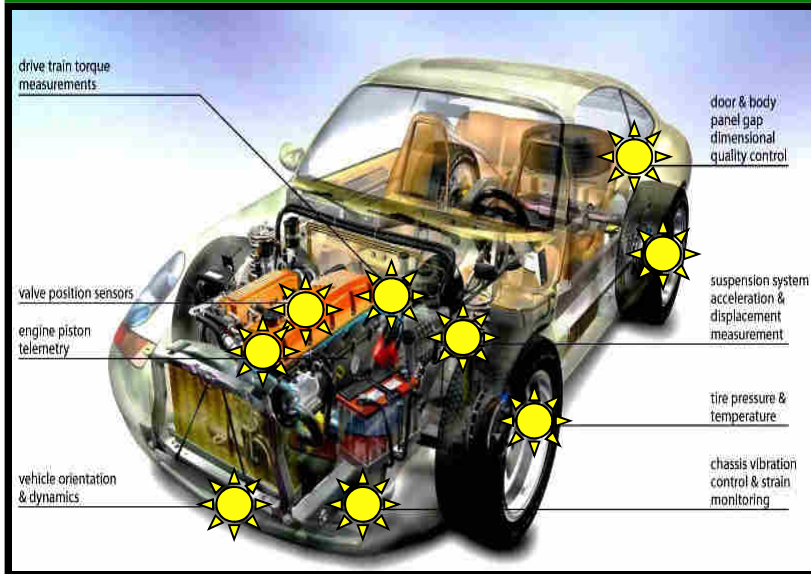
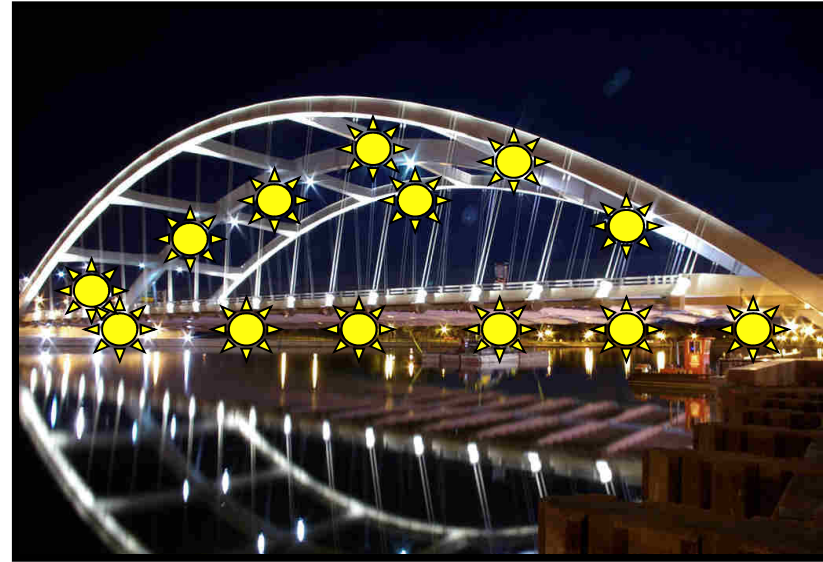
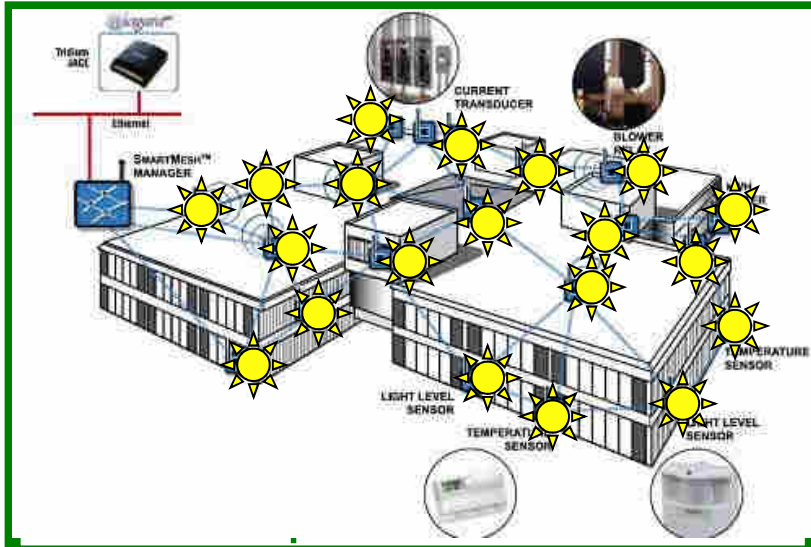
March 8, 2011



The planet will be instrumented,  
interconnected, intelligent  
People want it. We can do it.



 **Wireless Sensor Networks (WSN)**



## WSN market

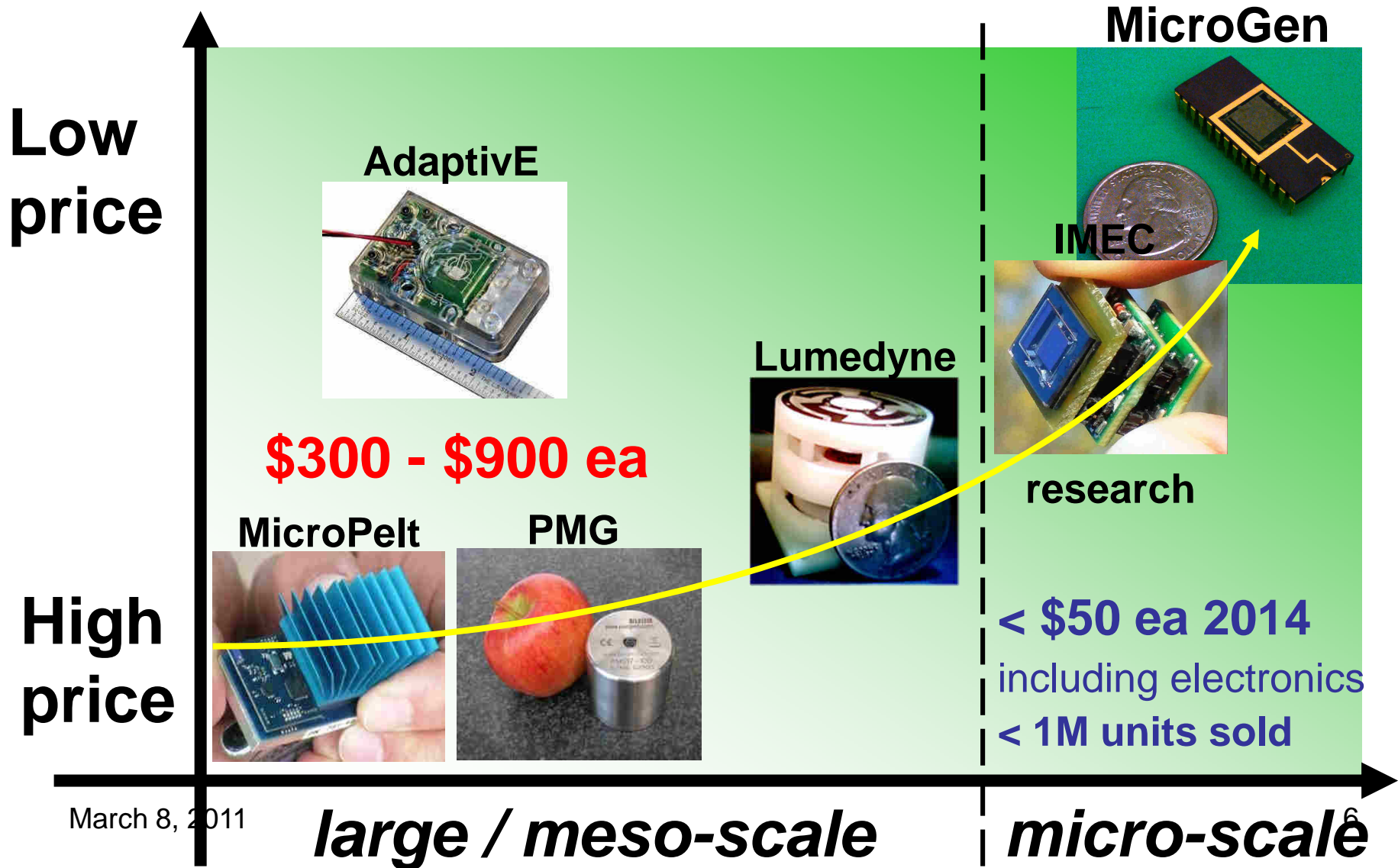
- **Cost of changing batteries** is holding back the market

Two (2) AA batteries →



wireless sensor node

# Meso to *micro*-scale



## 10X reduction in size

- Electrostatic force →  $10^2$  reduction
- Electromagnetic force →  $10^4$  reduction
- **Resistive power loss** → 100X greater loss
  - Due to higher electrical resistance
  - $P = V^2/R$
- **Manufacturing cost of MEMS coils**

**MEMS-based PZEH devices overcomes these issues and has the highest effective power density**

## Energy Harvesting “*plug-n-play*” boards

- Able to accept multiple EH inputs (solar, thermal, vibrational)
- Voltage rectifying and regulating electronics
- Power storage with efficient power management
  - Advanced thin-film rechargeable batteries; and/or
  - ultra-capacitors.
- Most integrated with sensors and/or wireless radios



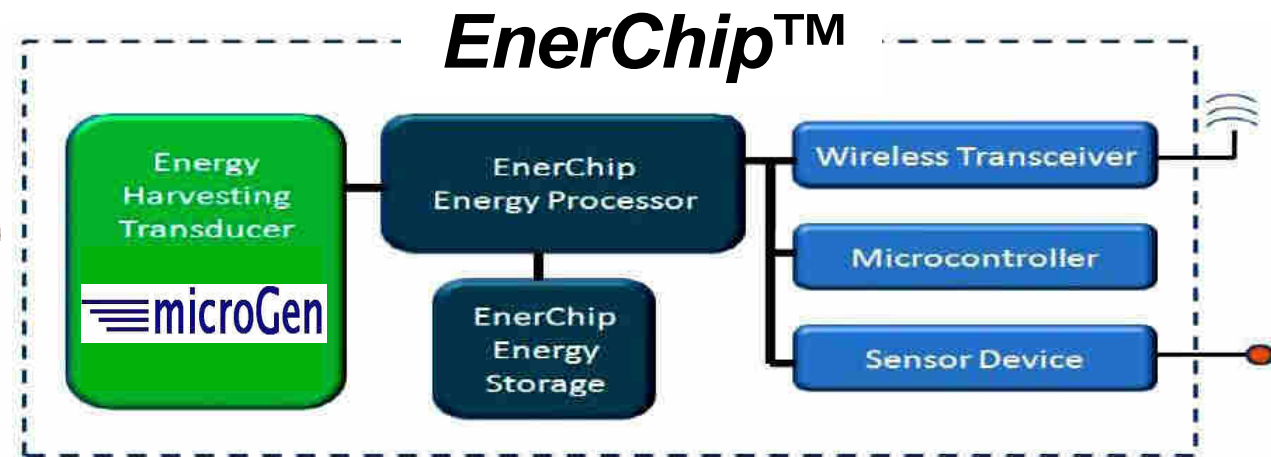
Advanced batteries,  
TI wireless radios



Ultra-cap,  
no radio



Both storage,  
wireless radio



“Integrating **MicroGen’s BOLT120A** micro-power generator producing a minimum of **100  $\mu$ Watts** (120 Hz and 1.0 g acceleration) will be more than enough power to charge **Cymbet’s Enerchip Energy Processor board** with advanced energy processing and storage (thin-film batteries), and will power a sensor device, microcontroller and allow the **Texas Instruments wireless radio** to **transmit and receive every 20-30 seconds**”

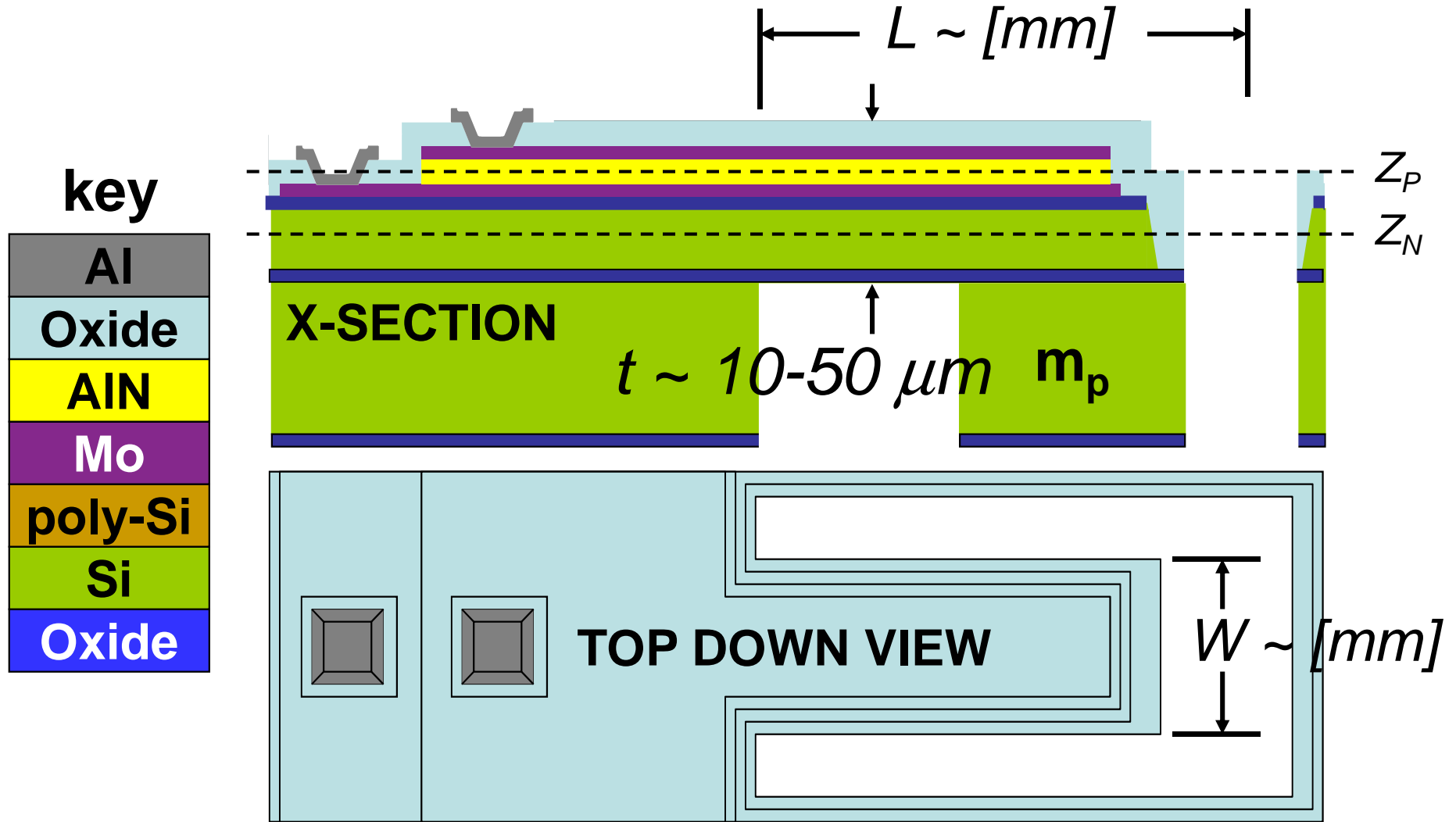
March 8, 2011

**Jeff Sather, VP Customer Solutions**

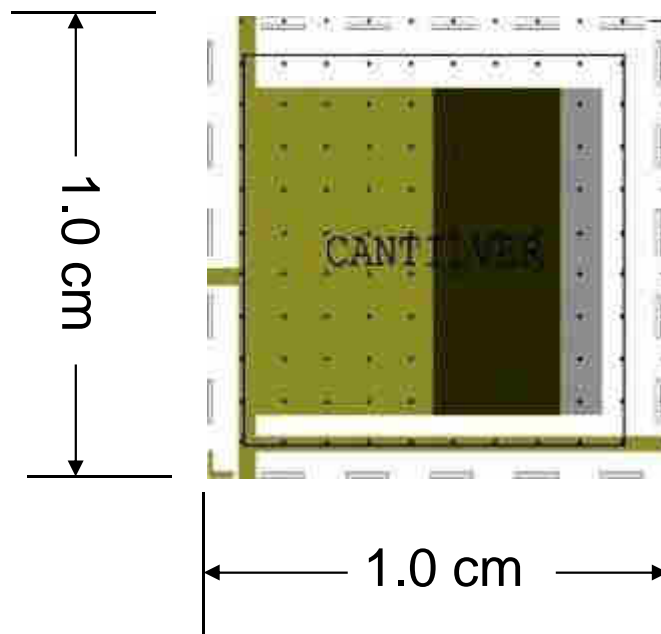
# **Piezoelectric Vibrational Energy Harvester (PZEH)**

1-axis and standard  
“bandwidth” PZEH device

# MEMS PZEH



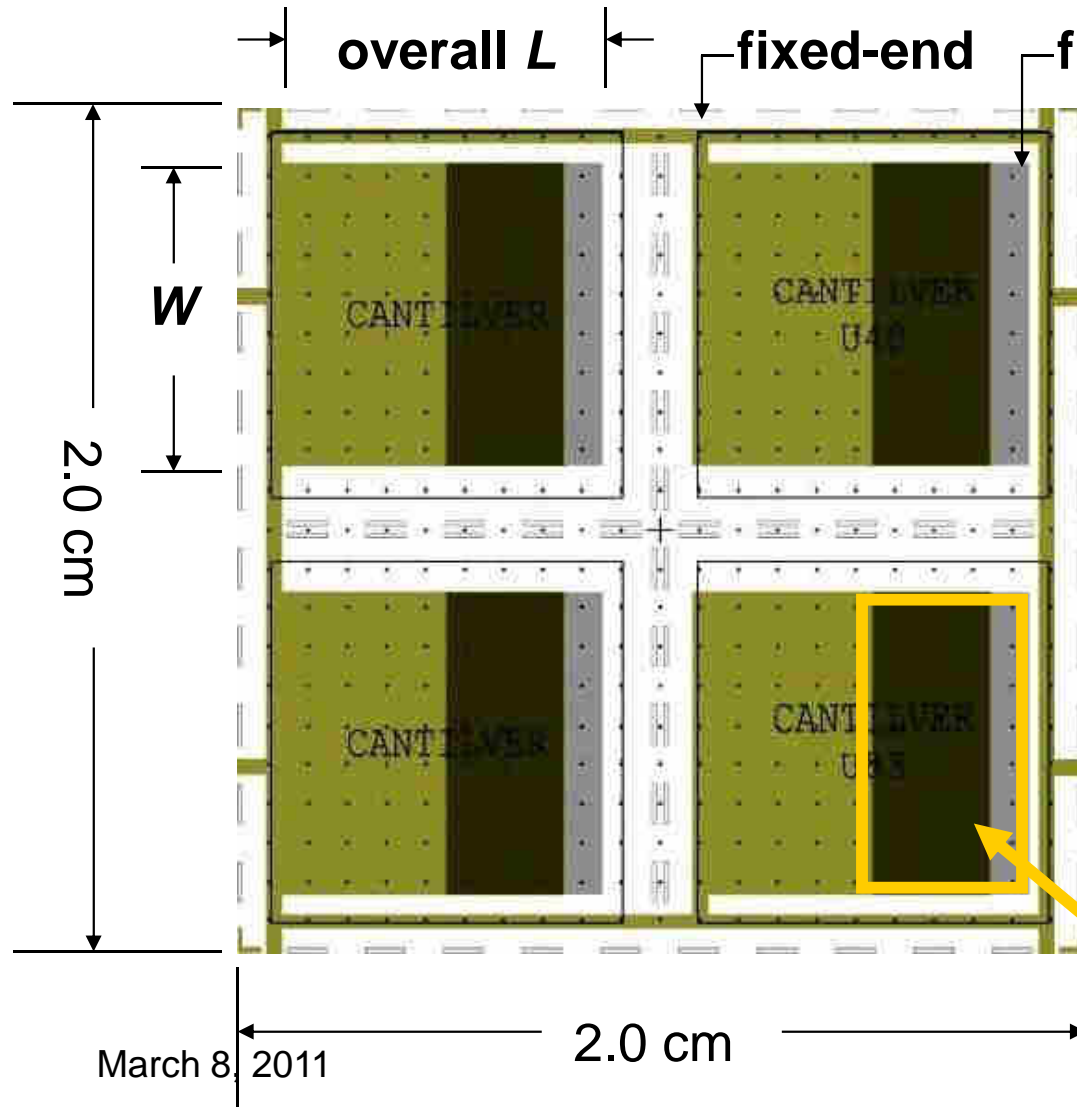
# “Single-chip”



- 1.0 x 1.0 cm die
- 1 cantilever
  - $W = W_i \sim [mm]'s$
  - $L = L_i \sim [mm]'s$
- Au proof (end) mass
- 2 electrical connections

**Top down view**

# “Quad-chip”



- 2.0 x 2.0 cm die
- 4 cantilevers
  - $W = W_i \sim [mm]'s$
  - $L = L_i \sim [mm]'s$
- End mass
- 2 electrical connections
  - All four (4) cantilevers in parallel

**End (proof) mass**

March 8, 2011

2.0 cm

$$V = \frac{Q_T}{C_p} \qquad C_p = \epsilon_o K_p \left( \frac{LW}{t_p} \right)$$

$$V_{z,\max} = \frac{1}{2\pi} \left( \frac{d_{31} E_p}{K_p} \rho \right) \left( \frac{t_p}{L} \right) (z_N - z_p) \left( \frac{G}{\epsilon_o \zeta V_1} \right) \left( \frac{k_{z,1} F_{z,1}(L)}{D_{z,1}(L)} \right)$$

**Voltage is linear with  $(z_N - z_p)$**

**Voltage is independent of  $W$**

**Voltage is inversely proportional to  $L$**

$$P = \frac{1}{2} C_p V^2 = \frac{1}{2} \frac{Q_T^2}{C_p} \quad C_p = \epsilon_o K_p \left( \frac{LW}{t_p} \right)$$

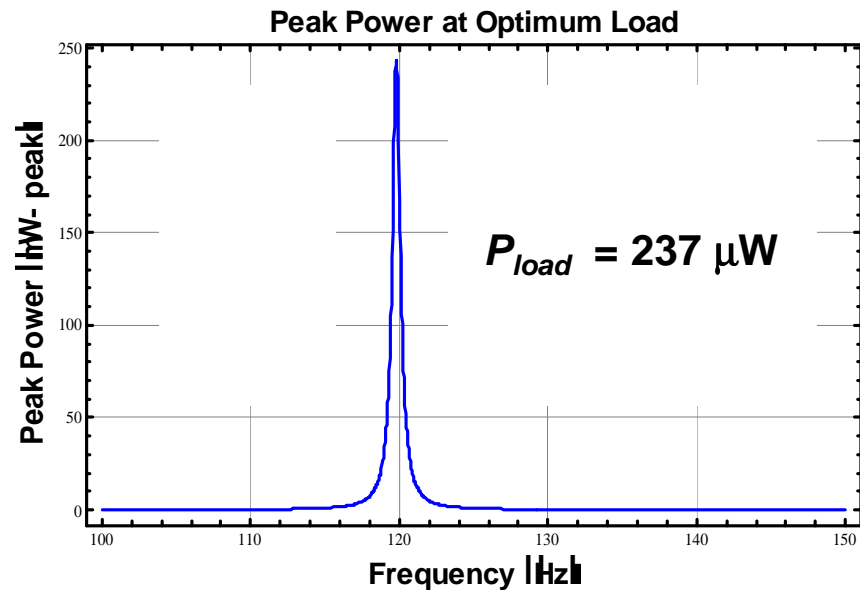
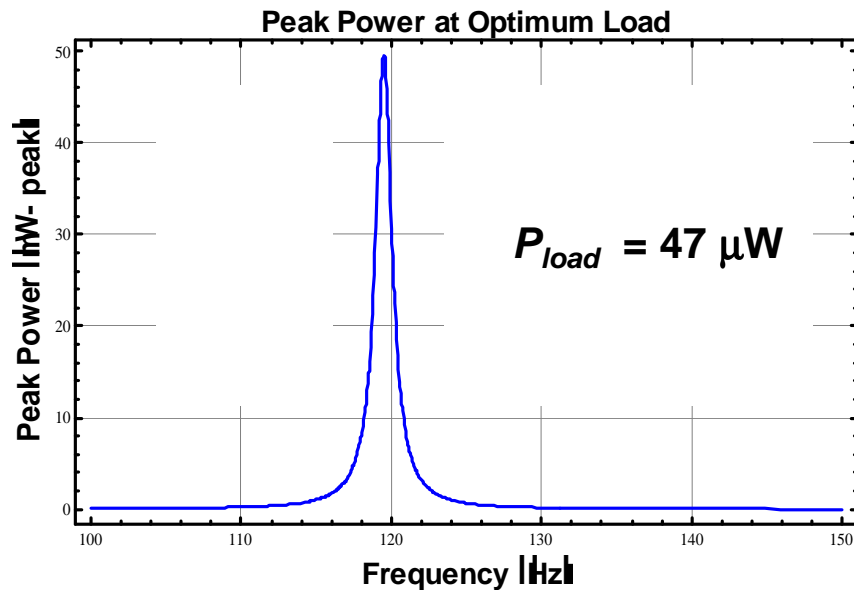
$$P = \frac{1}{8\pi^2} \left( \frac{d_{31}^2 E_p^2}{K_p} \rho^2 \right) \left( \frac{Wt_p}{L^2} \right) (z_N - z_p)^2 \left( \frac{A^2 G^2}{\epsilon_o \zeta^2 v_1^2} \right) \left( \frac{k_{z,1}^2 F_{z,1}^2(L)}{D_{z,1}^2(L)} \right)$$

**Power increases as  $(z_N - z_p)^2$**

**Power is proportional to  $W$**

**Power is inversely proportional to  $L^2$**

$P_{load}$  @  $\nu_1 = 120$  Hz and  $G = 1$  g



SOI device layer =  $t_{low}$

$$(z_N - z_p) \approx Z_{low}$$

$$\text{s.f.} \approx 2.75^*$$

SOI device layer =  $t_{high}$

$$(z_N - z_p) \approx Z_{high}$$

$$\text{s.f.} \approx 0.34^*$$

# AlN -vs- other piezos

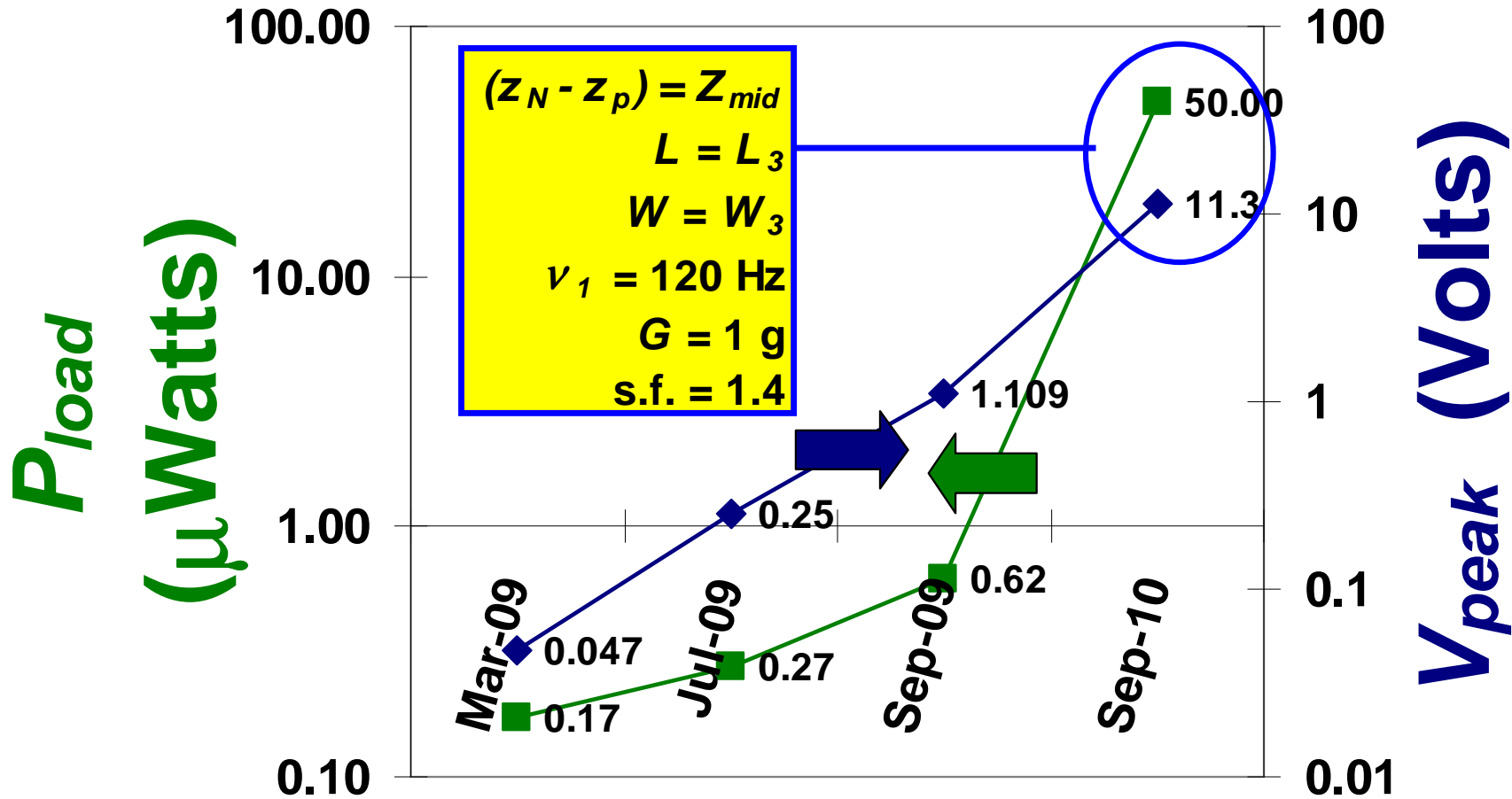
## Common piezoelectric materials.

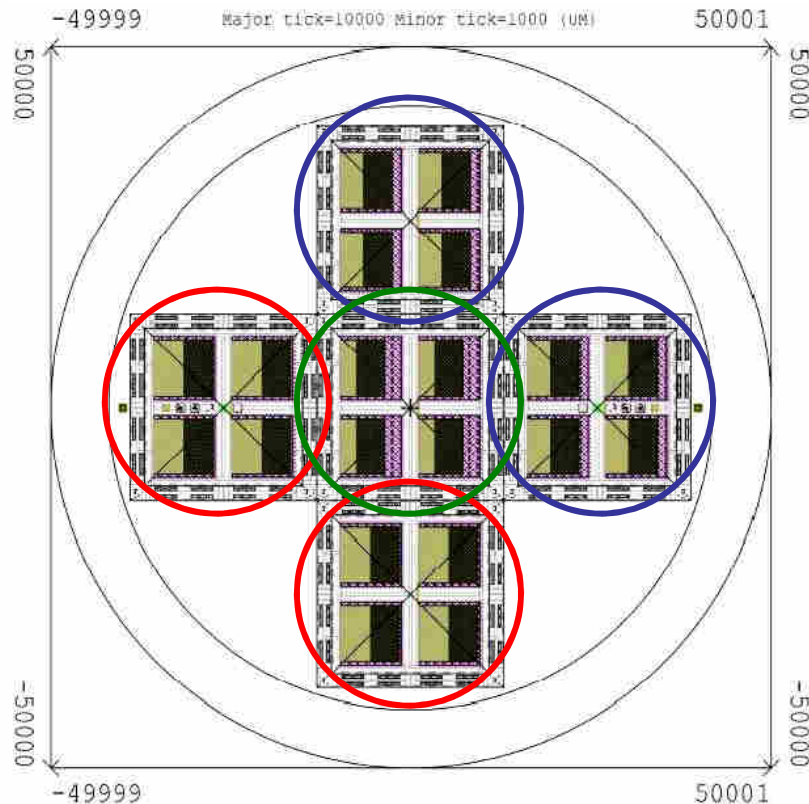
	coupling coefficient	Young's modulus	Dielectric constant	Density	Voltage material coefficients *	Power material coefficients *
Material	$d_{31}$ (pC/N)	$E_p$ (GPa)	$K_p$	$\rho$ (g/cc)	$\left[ \frac{d_{31} E_p}{K_p} \rho \right]$	$\left[ \frac{d_{31}^2 E_p^2}{K_p} \rho^2 \right]$
<b>AlN</b>	<b>-2</b>	340	<b>9</b>	3.26	<b>12.55</b>	<b>0.83</b>
LiNbO <sub>3</sub>	-0.85, -1	181.6	29, 85	4.644	<b>0.43 - 1.49</b>	<b>0.01 - 0.04</b>
BaTiO <sub>3</sub>	-34.5	67	1250 - 10,000	6.02	<b>0.07 - 0.57</b>	<b>0.03 - 0.24</b>
PVDF	20	3	12	1.78	<b>0.46</b>	<b>0.00</b>
Sol-gel PZT	<b>-44.2</b>	100	<b>1700</b>	7.55	<b>1.00</b>	<b>1.00</b>

\* values normalized to PZT

**AlN is much more manufacturable as well**

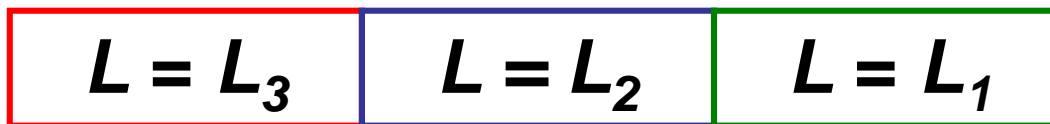
## Single-chip



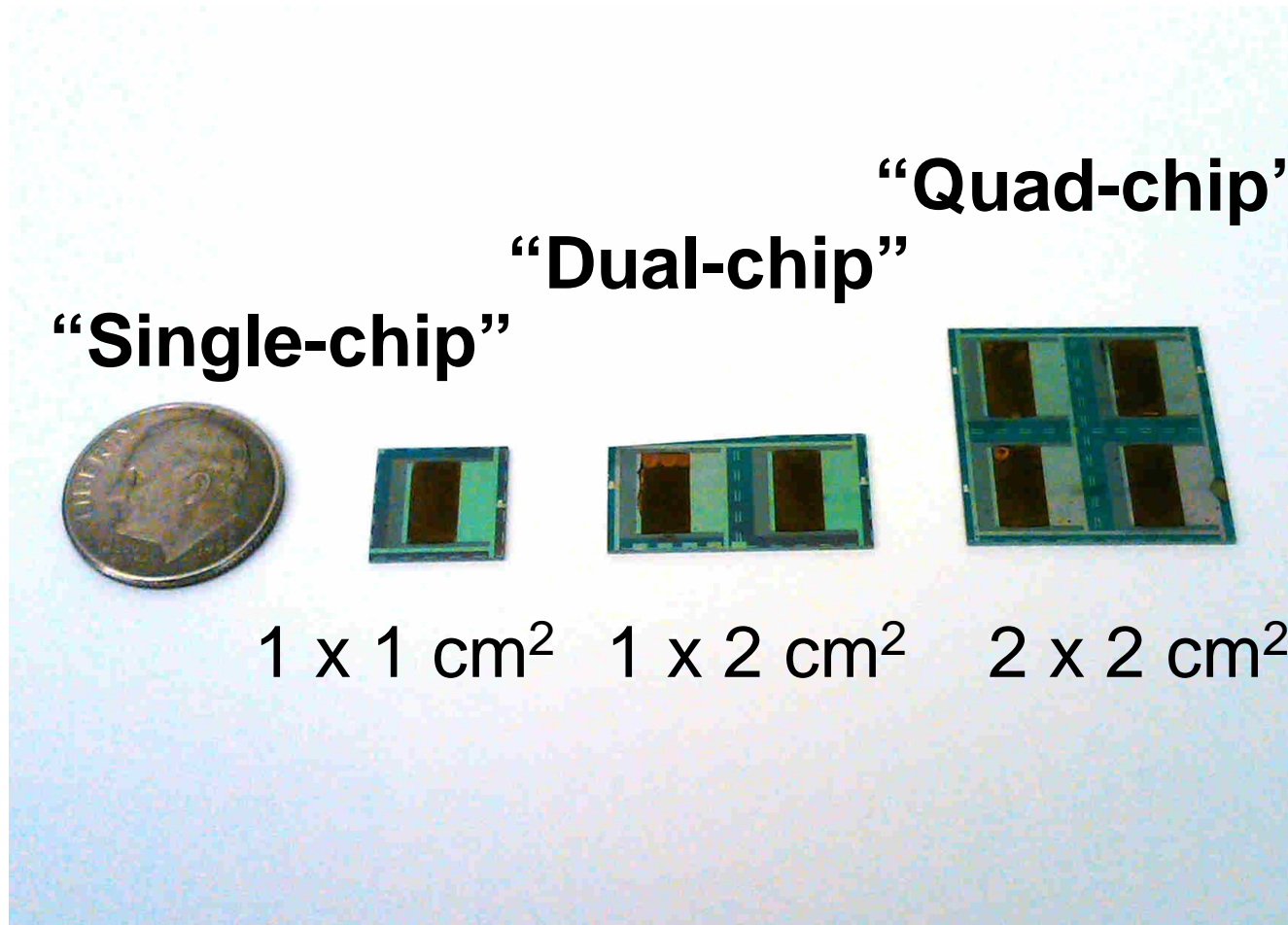


**$L$  and end-mass**  
varied to  
**optimize power**  
and evaluate  
cantilever  
**reliability**

(in progress)

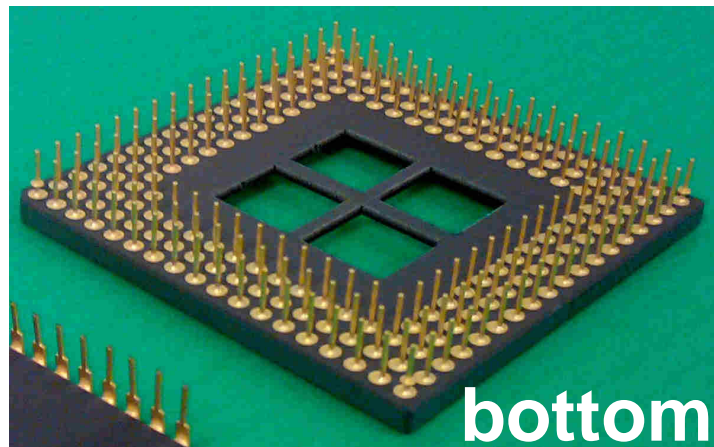
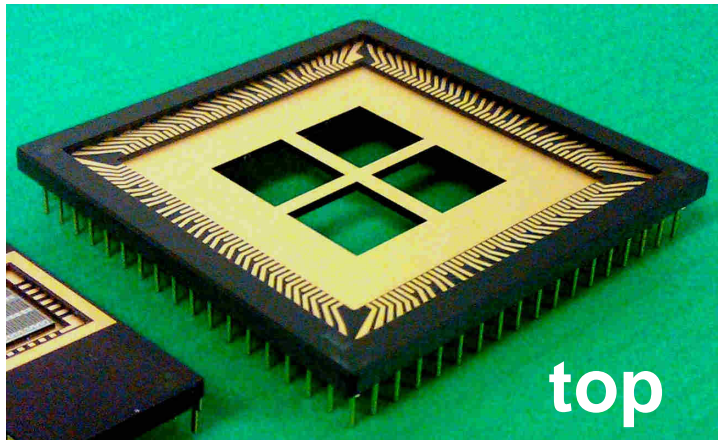


$$L_3 > L_2 > L_1$$

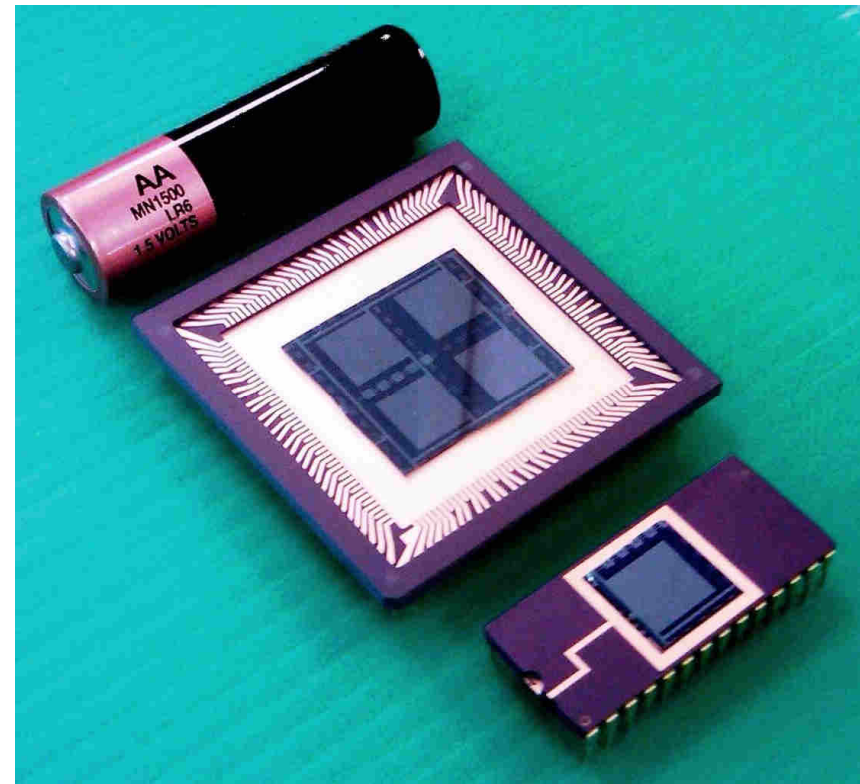


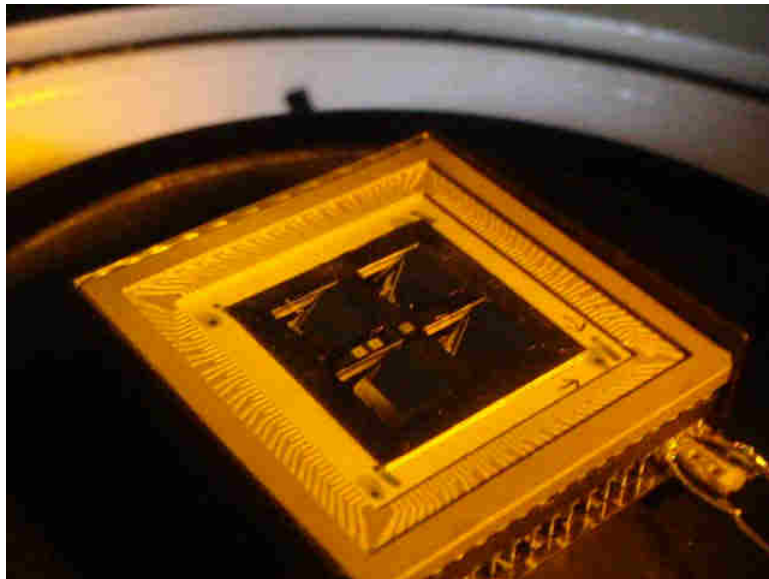
# Initial packaging

## milled demo package



## Packaged Quad-chip and Single-chip demo units





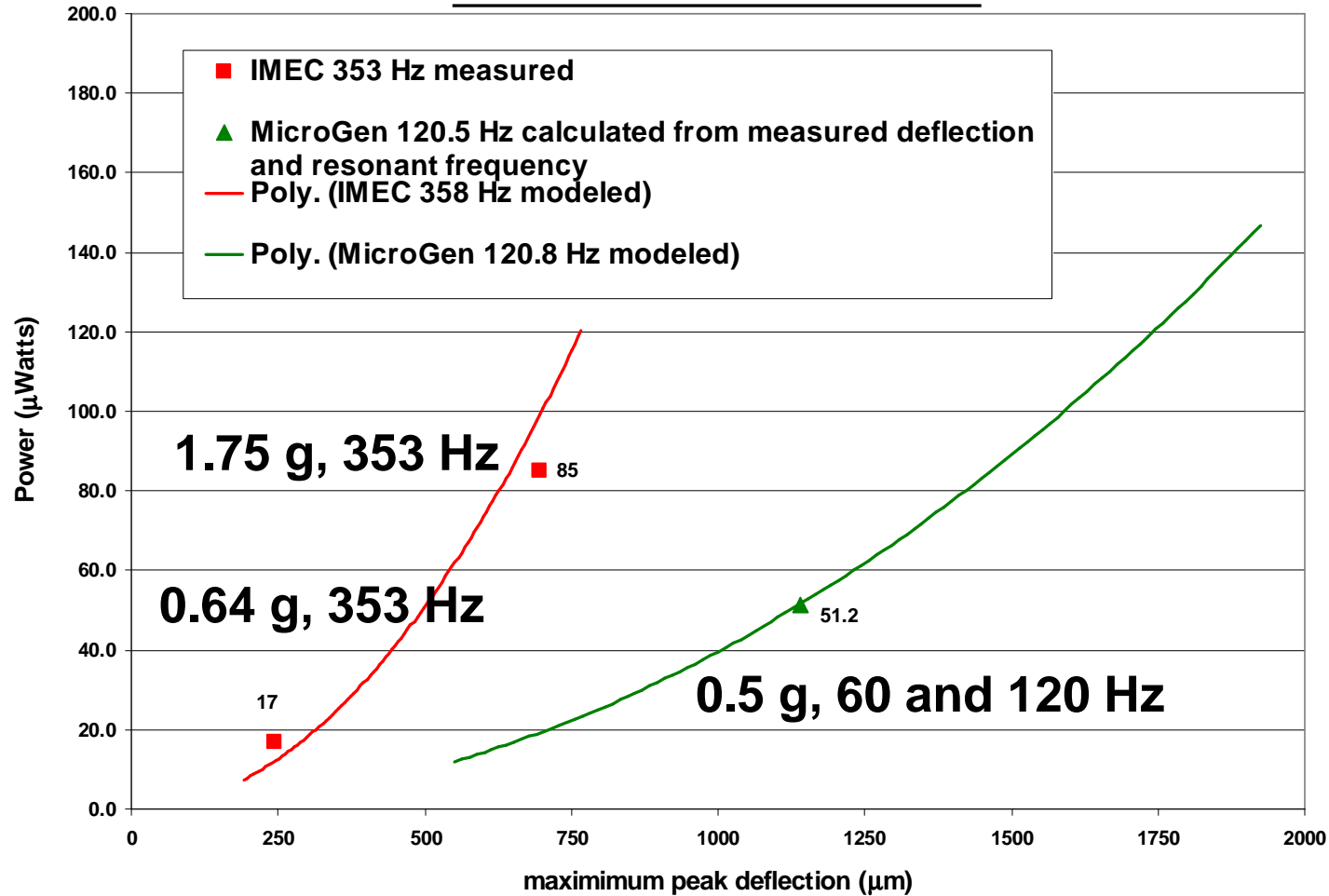
## Resonant frequency

- Cantilever to cantilever =  
=  $60 \pm 0$  Hz
- FWHM  $< 4$  Hz (as shown)

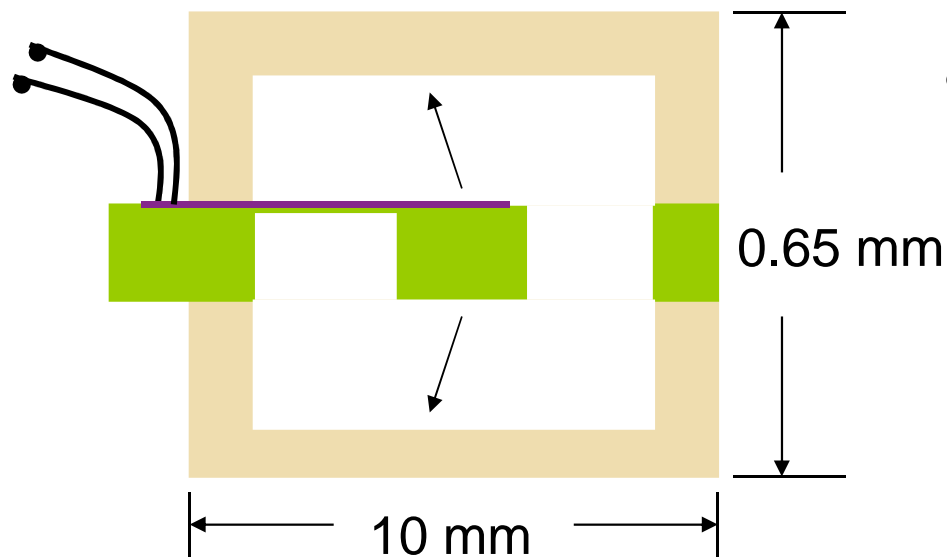
## G-acceleration (as shown)

- **$G = 0.5$  g**
- $\delta_{max}$  = deflection  $> \pm 2$  mm
- **Single-chip** ( $R_{load} < 20$  k $\Omega$ )  
–  **$P_{load} > 50$   $\mu$ Watts**
- **Quad-chip** ( $R_{load} < 5$  k $\Omega$ )  
–  **$P_{load} > 200$   $\mu$ Watts**

## MEMS mPZEH 1x1 cm<sup>2</sup> Chip



$$P \propto G^2$$



## Wafer / chip-scale packaging

- hermetically sealed

- Single-chip package
- New Director, Packaging and Test
  - **T. Gus McDonald**
    - TI's DMD DLP technology
    - Corning optical switch technology
    - **Major focuses**
      - Efficient packaging
      - Reliability testing

***BOLT™ Family of Products***  
generating ***100 μWatts*** minimum  
at ***constant G-level***

$\nu$ (Hz)	1.00 g	0.75 g	0.50 g	0.25 g	0.10 g
50 ± 2	<i>BOLT050A</i>	<i>BOLT050B</i>	<i>BOLT050C</i>	<i>BOLT050D</i>	<i>BOLT050E</i>
60 ± 2	<i>BOLT060A</i>	<i>BOLT060B</i>	<i>BOLT060C</i>	<i>BOLT060D</i>	<i>BOLT120E</i>
100 ± 2	<i>BOLT100A</i>	<i>BOLT100B</i>	<i>BOLT100C</i>	<i>BOLT100D</i>	<i>BOLT100E</i>
120 ± 2	<i>BOLT120A</i>	<i>BOLT120B</i>	<i>BOLT120C</i>	<i>BOLT120D</i>	<i>BOLT120E</i>

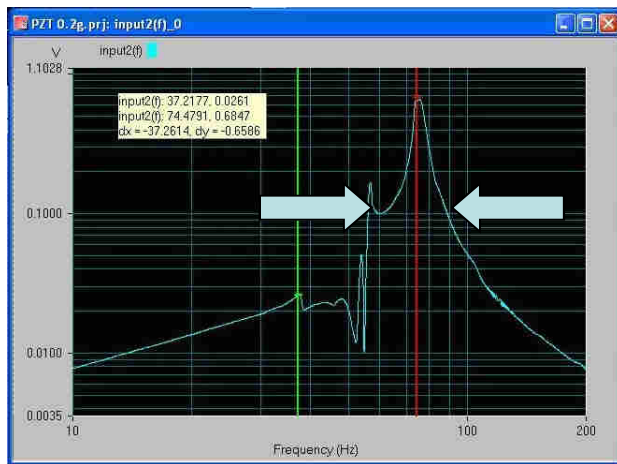
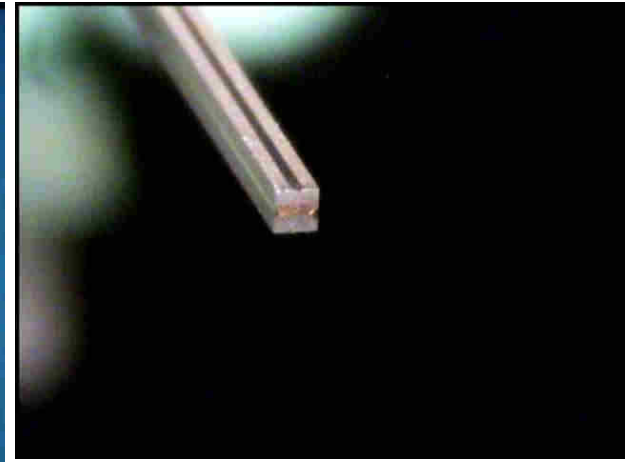
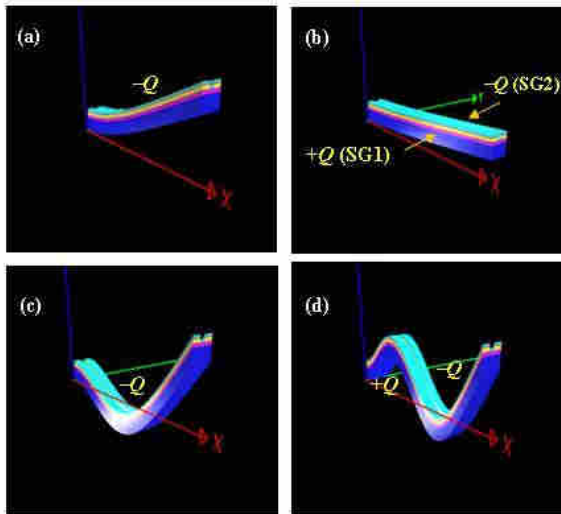
**BOLT050, BOLT060, BOLT100 and BOLT120 will be released as *Alpha*-products summer 2011**

- **Power enables EH-boards effectively**
  - > 50  $\mu\text{Watts}/\text{cm}^2$  unpackaged; > 75  $\mu\text{Watts}/\text{cm}^3$  packaged
  - We can obtain 2-4X power density in near-term
- **Price-point drops with volume**
  - < \$20 each at 1M/year
- **Reliability → 20+ years**
- **Overall packaged size < 0.7 cm<sup>3</sup>**

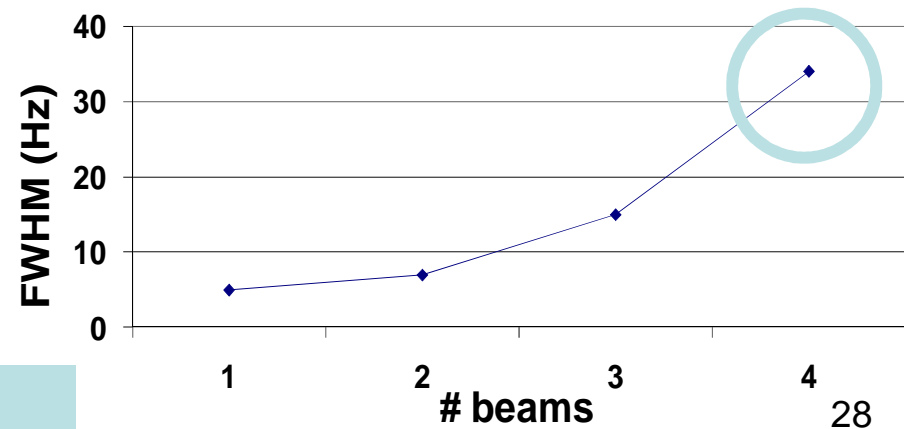
**Parametric Mode Enabled (PME)**  
or  
**Vibration Induced Broadband Excitation**  
**VIBE<sup>™</sup>**

**Multi-axis (2 and 3) and broadband**

International Patent Application Serial No. PCT/US08/57865, R.G. Andosca and J. Wu, entitled "Piezoelectric Vibrational Energy Harvesting Systems Incorporating Parametric Bending Mode Energy Harvesting," filed by UVM through DRM PLLC on March 21, 2008 (provisional March 21, 2007.)

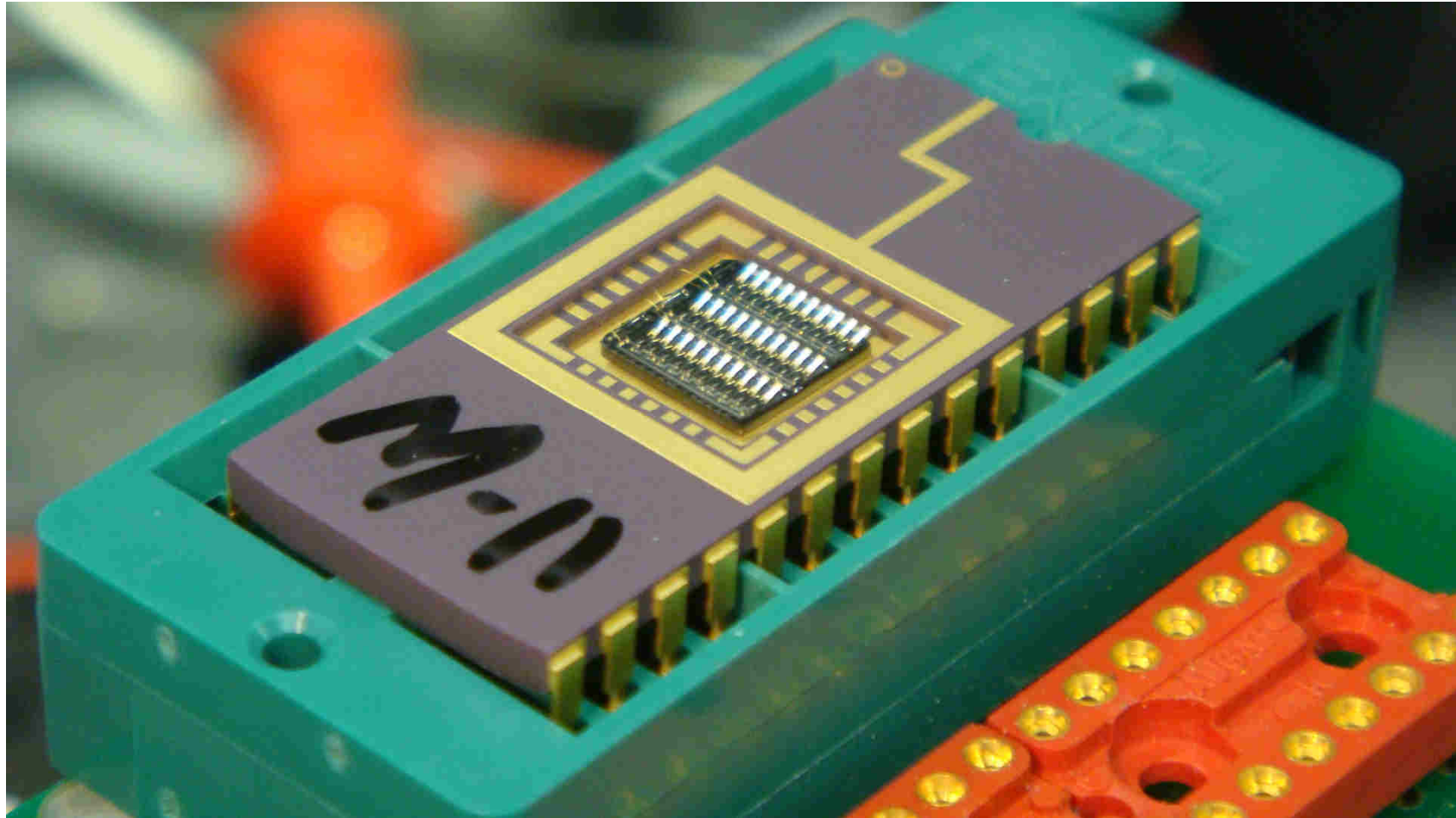


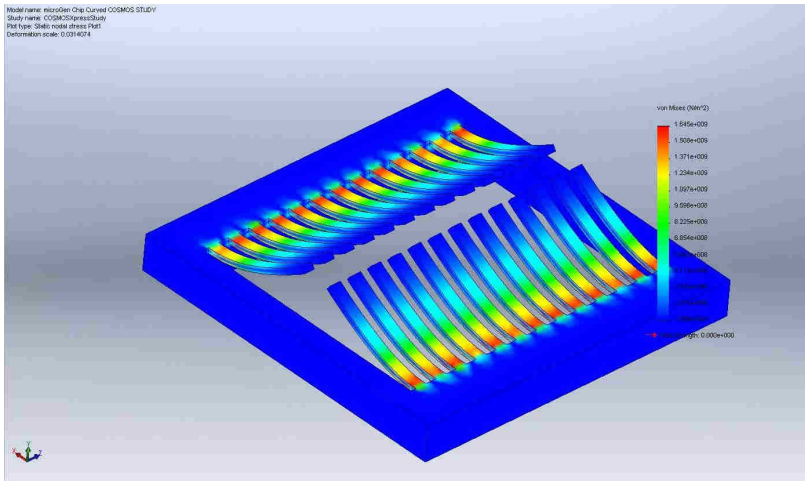
**Meso-scale PME-PVEH Bandwidth Broadening**



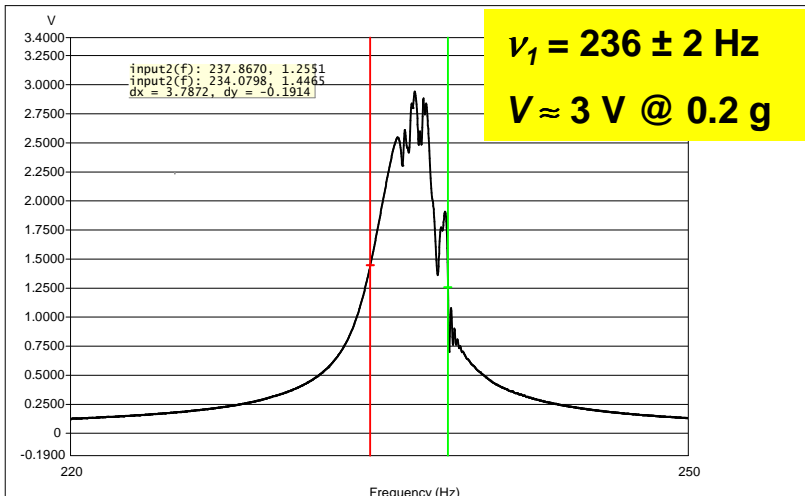
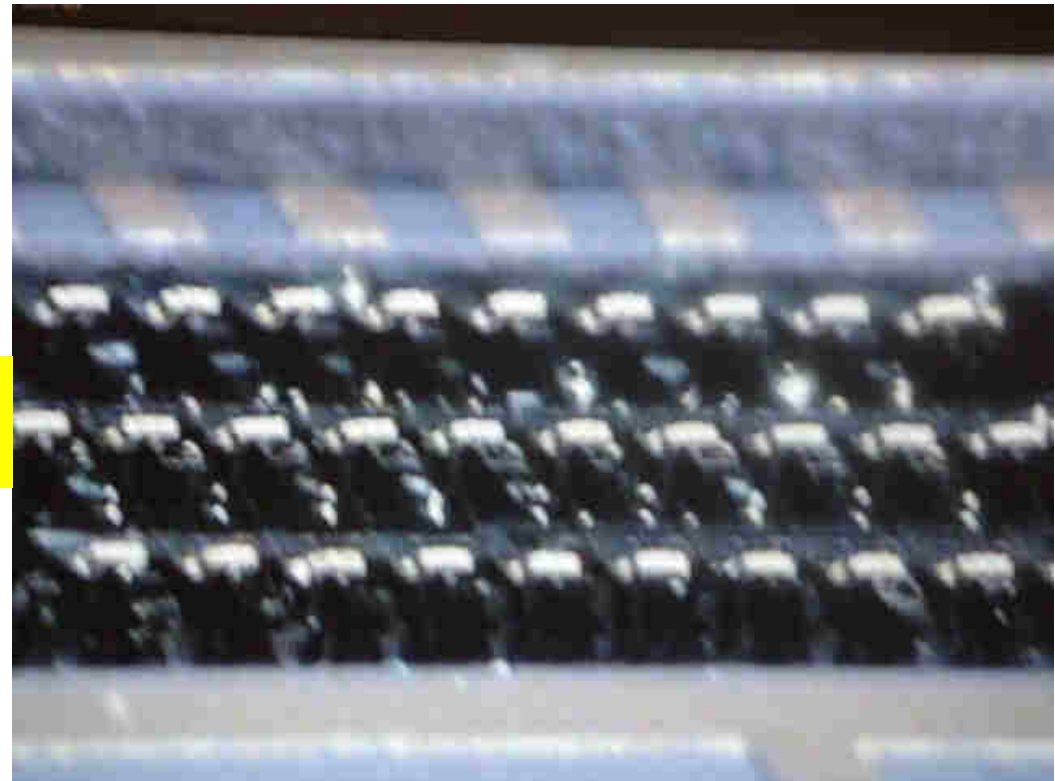
March 8, 2011

**$v_1 = 75 \pm 17 \text{ Hz}$**





## CANTILEVER END-VIEW



$\nu_1 = 240 \pm 2$  Hz within-die,  
 $\pm 5$  Hz die-to-die

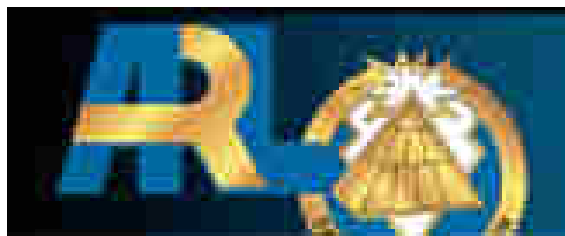
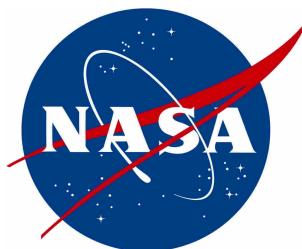
- **Monolithically multi-axis power generation**
- **Broad bandwidth – up to  $\pm 50$  Hz**
  - Random or shifting frequencies
  - Temperature compensation
- **Reliability  $\rightarrow$  20+ years**
- **Overall packaged size  $< 0.7$  cm<sup>3</sup>**

## “MicroGen signs MOU with Cornell’s Energy Materials Center EMC2 / NYSTAR”



# Acknowledgements

This work was funded in part by the following organizations



March 8, 2011



**Robert Andosca**

Founder, President and CTO

**MicroGen Systems, Inc.**

Cornell Business and Technology Park

95 Brown Rd., Suite 129, MS 1014

Ithaca, NY 14850

**(617) 447-1876 cell**

(607) 237-3001 main

[randosca@microgensystems.com](mailto:randosca@microgensystems.com)

---

## Over 100 years combined experience

- ~ Balanced team with core skill sets
- ~ Management / Product Development roles
- ~ 18 startups to large companies
- ~ \$17 M capital raised ~ 20 product launches

**Robert Andosca, Founder, CTO** – 20+ yr MEMS Expert; MS/PhD (ABD) UVM

**David Hessler CEO** – Xerox, Serial ENT, VC; MS / MBA UMICH

**Michael Perrotta CFO/COO** – Kodak, Serial ENT; BS Eng, MBA Simon

**Junru Wu, Founder, Tech Fellow** – Vibration Expert; MS/PhD UCLA

## MEMS and Semiconductor

- **Matthias Wagner**, Former CEO, **Redshift Systems** and **Aegis Semiconductor**, MA
- **Roger Grace**, President, **Roger Grace Associates** (marketing), FL
- **Dr. Les Fritze**, CEO, **Wakonda Technology** (photovoltaic), MA
- **Andrew Tucker**, VP North American Field Operations, **SPP Process Technology Systems** (semiconductor/MEMS equipment manufacturer), MA, USA & Wales, UK

## Micro-power Systems, Sensors and WSNs

- **Skip Ashton**, Sr. VP Engineering, **Ember Corporation** (WSN), MA
- **Dr. Mark Bocko**, CEO, **ADVIS** (sensors, ASIC design); Chair & Professor EECS, **U of R**, NY
- **Jim Cantin**, CEO, **Leveraging Technology** (WSN software communications), NY
- **Steve Grady**, VP Marketing, **Cymbet Corporation** (advanced batteries), MN
- **Peter Tsepellef**, CEO, **Grape Networks** (WSN), CA

## Vibration and piezoelectrics

- **Dave Henderson**, CEO, **NewScale Technologies**, NY
- **Dr. Junru Wu**, Technical Fellow, **MicroGen**; Professor Physics, **UVM**, VT

- 
- [1] R. Andosca, and J. Wu, "Energy Harvesting: Meso to Micro-scale Technologies", **invited speaker to "Extreme Electronics/MEMS – Energy" Session of SEMICON West**, San Francisco, CA, July 13, 2010.
  - [2] R.G. Andosca and J. Wu, "Efficient vibrational power harvesting – Analytical solutions and design concepts", **Journal Acoustical Society of America**, submitted for publication June 2010.
  - [3] **MicroGen internal patent disclosure**, "MEMS-based Piezoelectric Vibrational Energy Harvester and Highly-Manufacturable Method of Manufacture", R.G. Andosca inventor (filed January 2010, and provisional patent application to be filed in 2010).
  - [4] **MicroGen internal patent disclosure**, "MEMS-based Parametric-Mode-Enabled Piezoelectric Vibrational Energy Harvester and Method of Manufacture", R.G. Andosca inventor (filed January 2010, and provisional patent application to be filed in 2010).
  - [5] R.G. Andosca, **Invited panelist** for "Energy and Environmental Sensing" Session of MEMS Executive Congress (organized by the MEMS Industry Group), Sonoma, CA, November 4-6, 2009.
  - [6] R. Andosca, K. Lee, N. Stoffel, J. Wu, P. Tspellef, and M. St. Germaine, "MEMS Energy Harvesting for WSN", **invited speaker** to the 2009 Sensors Expo and Conference, Rosemont, IL, June 8-10, 2009.
  - [7] R. Andosca, K. Lee, and J. Wu, "Efficient Vibrational Energy Harvesting for WSN", **invited speaker** to the NanoPower Forum Workshop/Darnell Group, San Jose, CA, May 18-20, 2009.
  - [8] International Patent Application Serial No. PCT/US08/57865, R.G. Andosca and J. Wu, entitled "Piezoelectric Vibrational Energy Harvesting Systems Incorporating Parametric Bending Mode Energy Harvesting," filed by UVM through DRM PLLC on March 21, 2008.
  - [9] U.S. Provisional Patent Application 60/896,077, "MEMS-Based Vibrational Power Scavenger," UVM, R.G. Andosca and J. Wu, filed March 21, 2007.

March 8, 2011